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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet 2

of 2

Application Number 10/823,849
Filing Date APRIL 13, 2004
First Named Inventor YEUK-FAI MOK, ET AL.
Group Art Unit ~~2812~~ 2818
Examiner Name UNKNOWN David Vu
Attorney Docket Number AMAT/8298/CMP/ECP/RKK
Submission Date 7/30/04

NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No.†	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T ²
DV	C1	COLOMBO, "Wafer Back Surface Film Removal", Central R&D, SGS-Thomson Microelectronics, Agrate, Italy, Spin Tech Technology, 6 pages, unknown date	
	C2	HOLM, Electric Contacts Theory and Application, Fourth Completely Rewritten Edition, Springer-Verlag, New York Inc., August 21, 1967, 27 pages.	
	C3	JIANG, et al., "Variations in Cu CMP Removal Rate Due to Cu Film Self-Annealing", Advanced Metallization Conference in 1998 (AMC 1998), 8 pages.	
	C4	PITNEY, "NEY Contact Manual", Electric Contacts for Low Energy Uses, 1973.	
	C5	SIMPSON, et al., "The Electrical Integrity of Copper Plated Wafers Using a Novel Plating Bath Chemistry" Slides Publicly Disclosed, 13 Pages October 17-22, 1999.	
	C6	SINGER, "Tantalum, Copper and Damascene: The Future of Interconnects," Semiconductor International, June 1998, Pages cover, pages 91-94, 96, & 98.	
	C7	SINGER, "Wafer Processing", Semiconductor International, June, 1998, page 70.	
	C8	Laurel Technologies Corporation from www.laurell.com , "Two control configurations available- seeWS 400 OR WS-400Lite." 1998, 6 pages.	
	C9	Welcome to Verteq Online Products Overview, from Verteq from www.verteq.com , unknown date	
	C10	"Metallization & Interconnect", Semitool, Inc., 1998, 4 pages	
	C11	European Search Report from EP 0 110 3525 dated July 10, 2001.	
	C12	European Search Report for Application 301415.6 dated December 11, 2000.	
DV	C13	Austrian Patent Office Search report for Application 00010504 ; unknown date	

Examiner

Finland

Date Considered 10/30/05

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